



Differential, Gauge and Absolute Compensated Pressure Sensor (0 to 100 kPa)

MPXx2100

Last Updated: Feb 3, 2026

As of February 2, 2026, NXP MEMS sensor products have been transitioned to STMicroelectronics. For more information, contact STMicroelectronics.

The MPX2100 pressure sensor series offers silicon piezoresistive solutions for a diverse array of medical and industrial applications.

- Provides a highly accurate and linear voltage output directly proportional to the applied pressure
- Includes a single monolithic silicon diaphragm with the strain gauge and a thin-film resistor network integrated on-chip
- Delivers a laser-trimmed chip for precise span, offset calibration and temperature compensation

MPXX2100_BD Block Diagram

PACKAGING ORDERING INFORMATION

Device Type	Packing Options	Case
MPX2100A	Absolute, Differential	344
MPX2100D	Absolute, Differential	344
MPX2100DP	Differential, Dual Port	344C
MPX2100AP	Absolute, Gauge	344B
MPX2100GP	Absolute, Gauge	344B
MPX2100ASX	Absolute, Gauge Axial	344F
MPX2100GSX	Absolute, Gauge Axial	344F

View additional information for [Differential, Gauge and Absolute Compensated Pressure Sensor \(0 to 100 kPa\)](#).

Note: The information on this document is subject to change without notice.

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